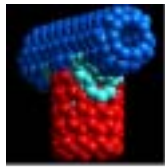




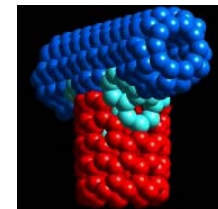
# Nanotechnology: *Impact on Metrology*



M. Meyyappan and Cattien V. Nguyen  
NASA Ames Research Center  
Moffett Field, CA 94035  
m.meyyappan@nasa.gov

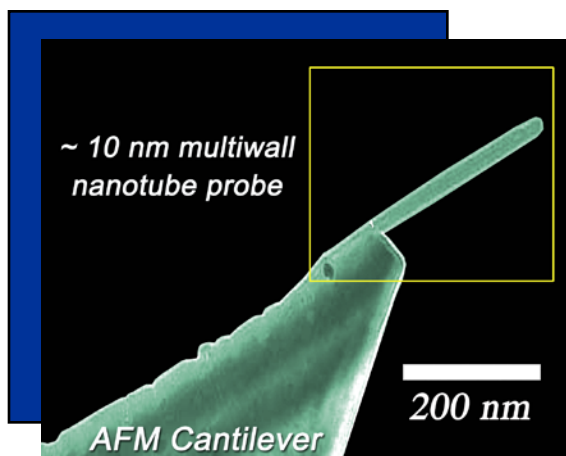
Acknowledgement: Jeff Sun, Bin Yu.

# CNT in Microscopy

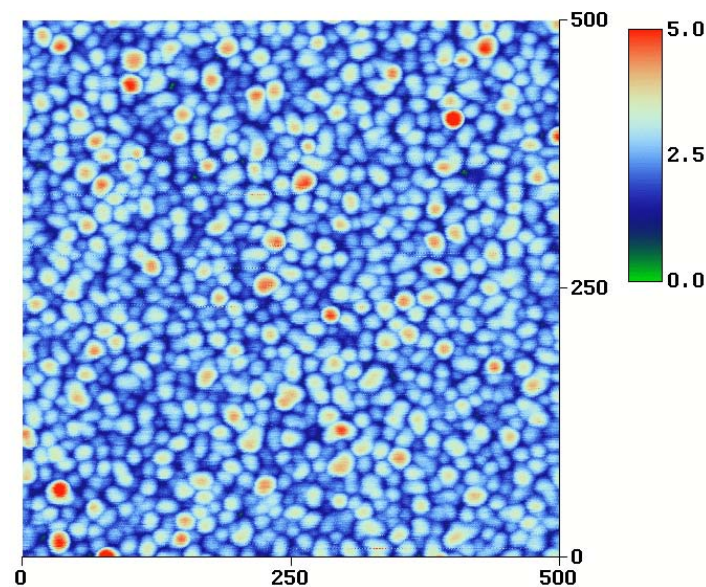


Atomic Force Microscopy is a powerful technique for imaging; also CD metrology, nanomanipulation, as platform for sensor work, nanolithography...

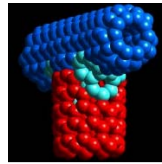
Conventional silicon and other tips wear out quickly. **2 nm thick Au on Mica imaged with SWCNT**  
 CNT tip is robust, offers amazing resolution.



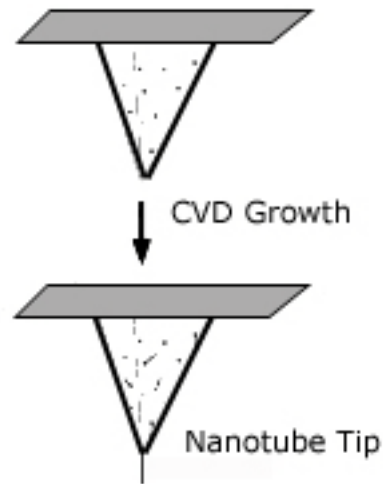
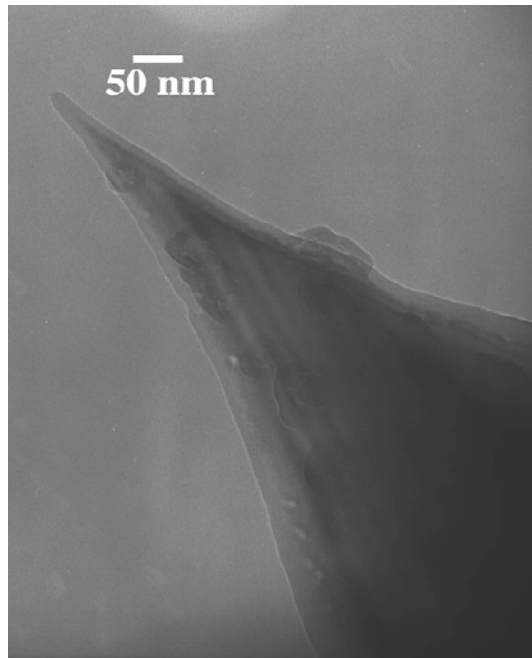
Simulated Mars dust



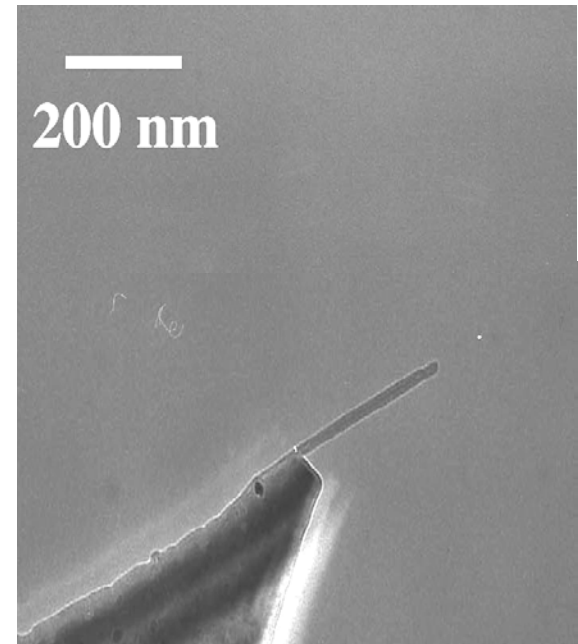
# Fabrication of CNT Probes



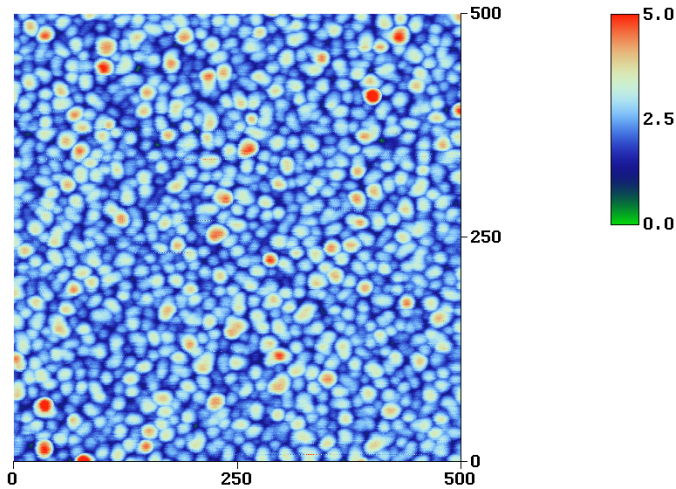
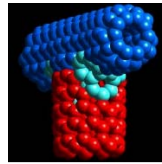
Transition metal catalyst is deposited from liquid phase or sputtered on the tip of the cantilever



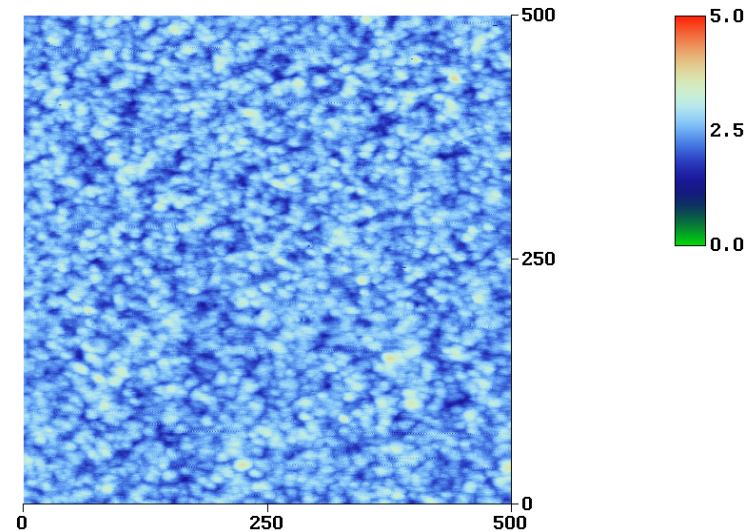
Carbon nanotube is grown in thermal CVD or plasma reactor



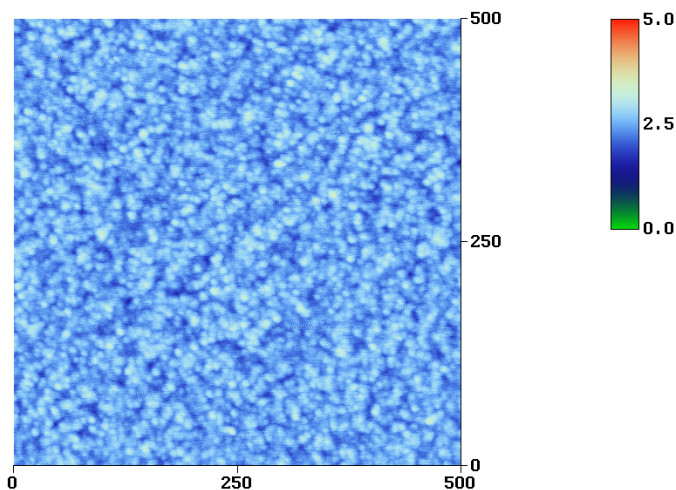
# AFM Imaging with Single Wall Nanotube Tips



2 nm thick Au on Mica



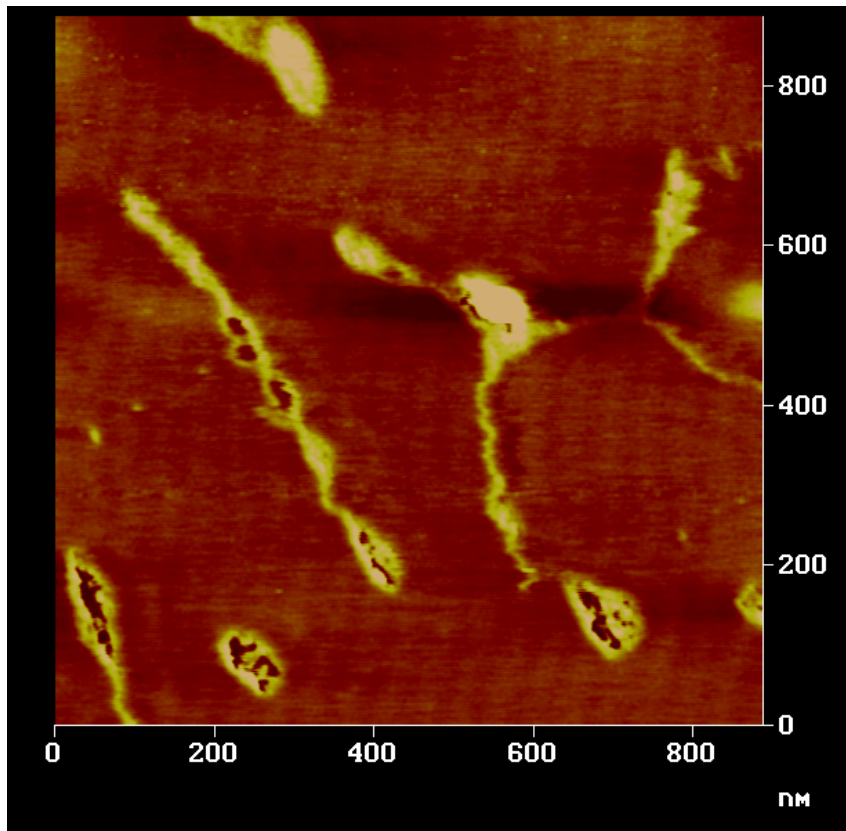
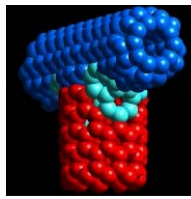
Si<sub>3</sub>N<sub>4</sub> on Silicon substrate



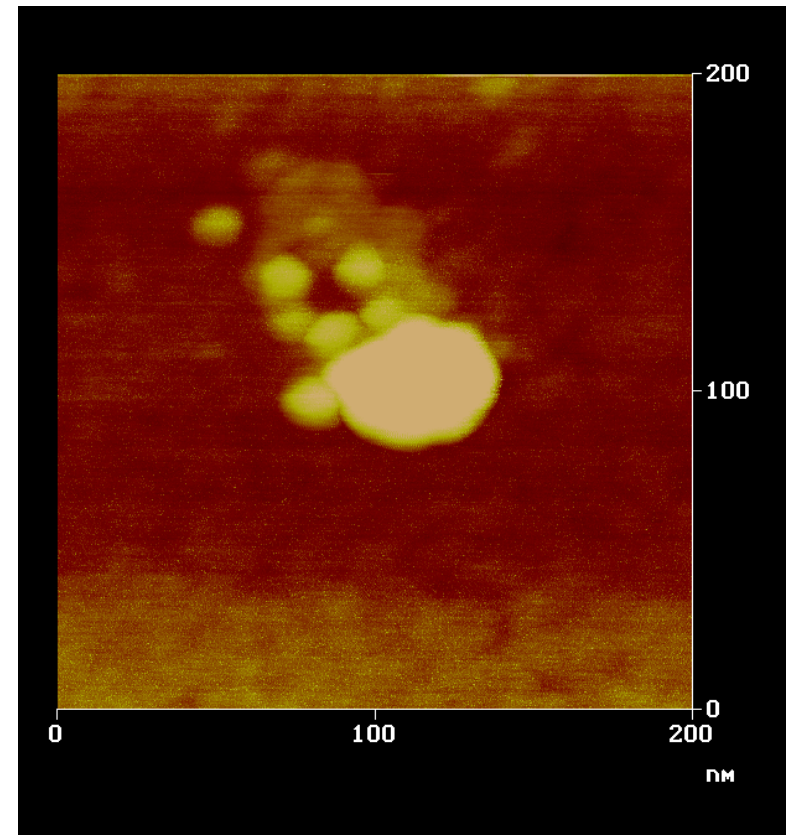
5 nm thick Ir on Mica

- Remarkable nanoscale resolution is evident
- More importantly, the same high resolution is maintained with continued use of the probe for a long time; probe doesn't wear out easily.

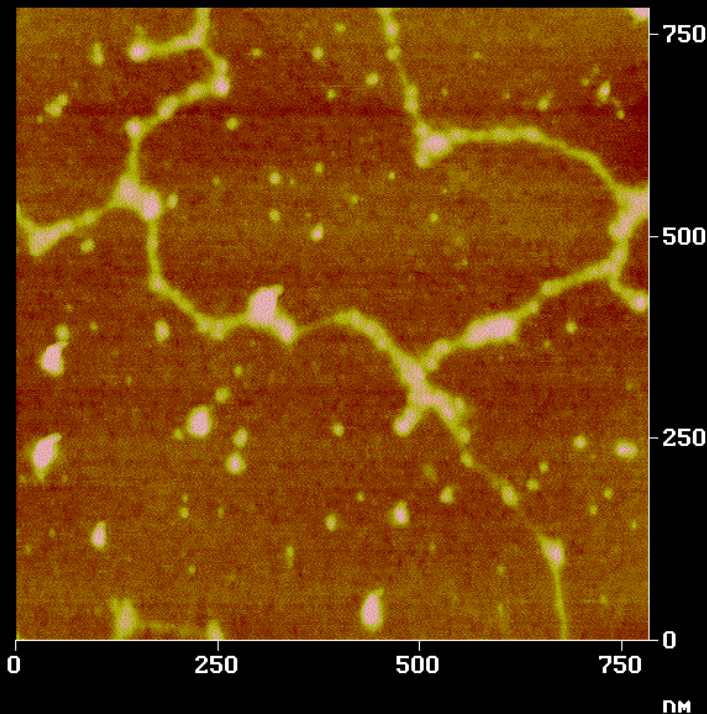
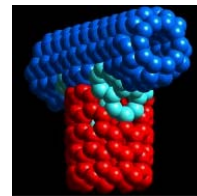
*Nguyen et al., Nanotechnology, 2001, Vol. 12, p. 363.*



DNA



PROTEIN



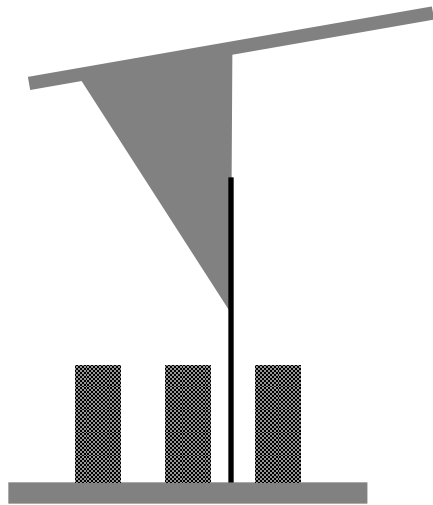
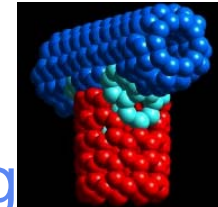
*DNA on mica in 20 mM Tris HCl and 10 mM magnesium chloride solution (near physiological conditions)*

- The hydrophobic nature of the CNT graphitic sidewall is chemically incompatible with aqueous solutions. Probes are unstable when submerged in solution.
- The CNT probe is treated with a ethylene diamine coating, rendering it hydrophilic.

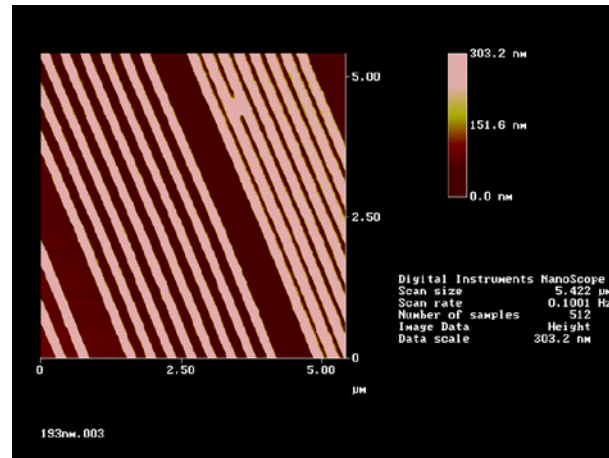
R.M. Stevens et al, IEEE Trans. Nanobioscience Vol. 3, pp. 56-60 (2004).

# MWNT Scanning Probe:

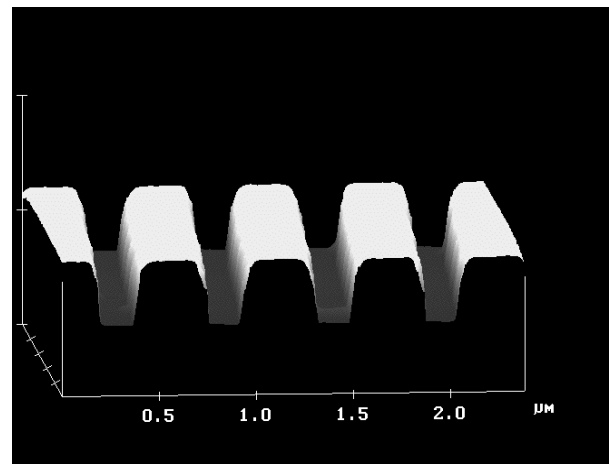
## Profilometry in Semiconductor Manufacturing

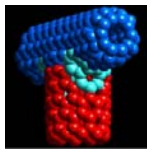


193 nm IBM Version 2 Resist

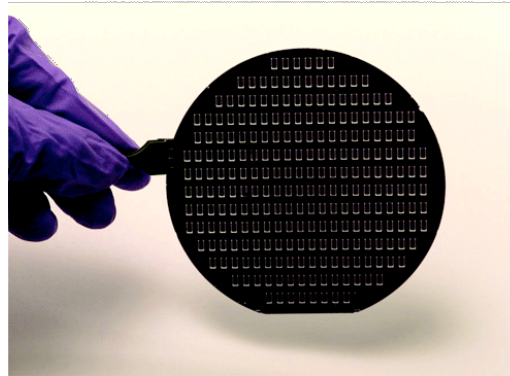


DUV Photoresist Patterns Generated by Interferometric Lithography



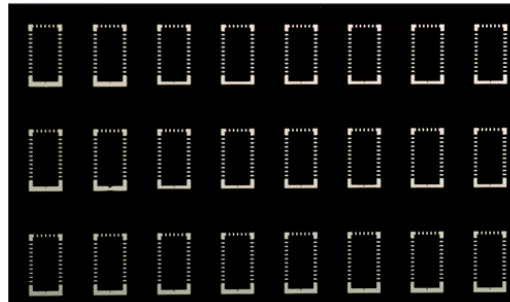


(a)



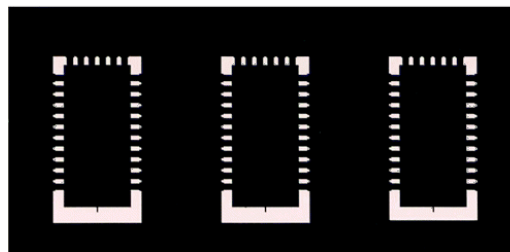
4" wafer with 244 probes

(b)



8 x 3 array

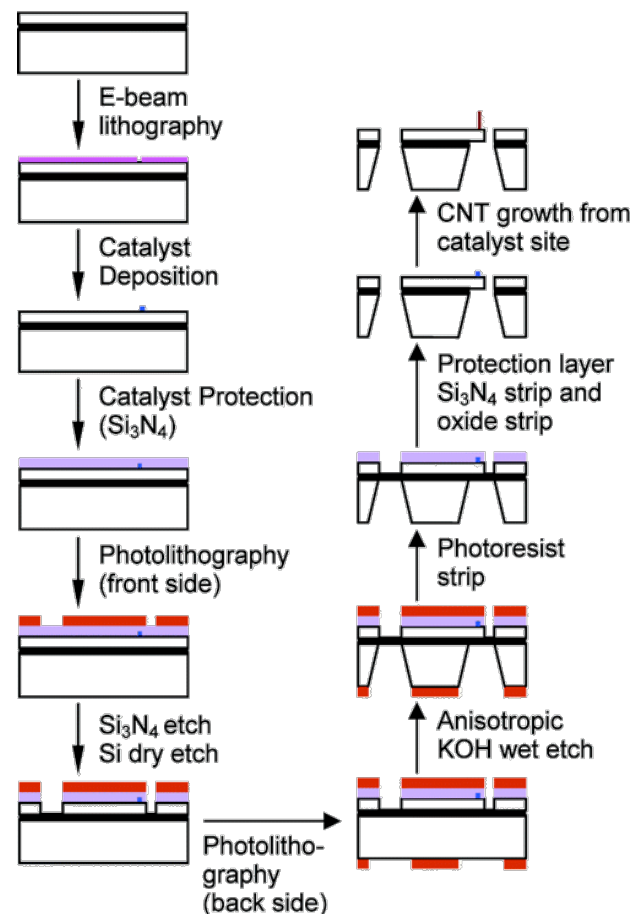
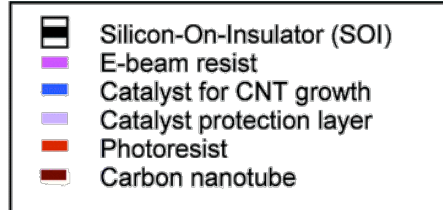
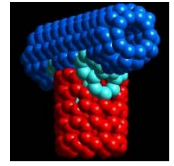
(c)

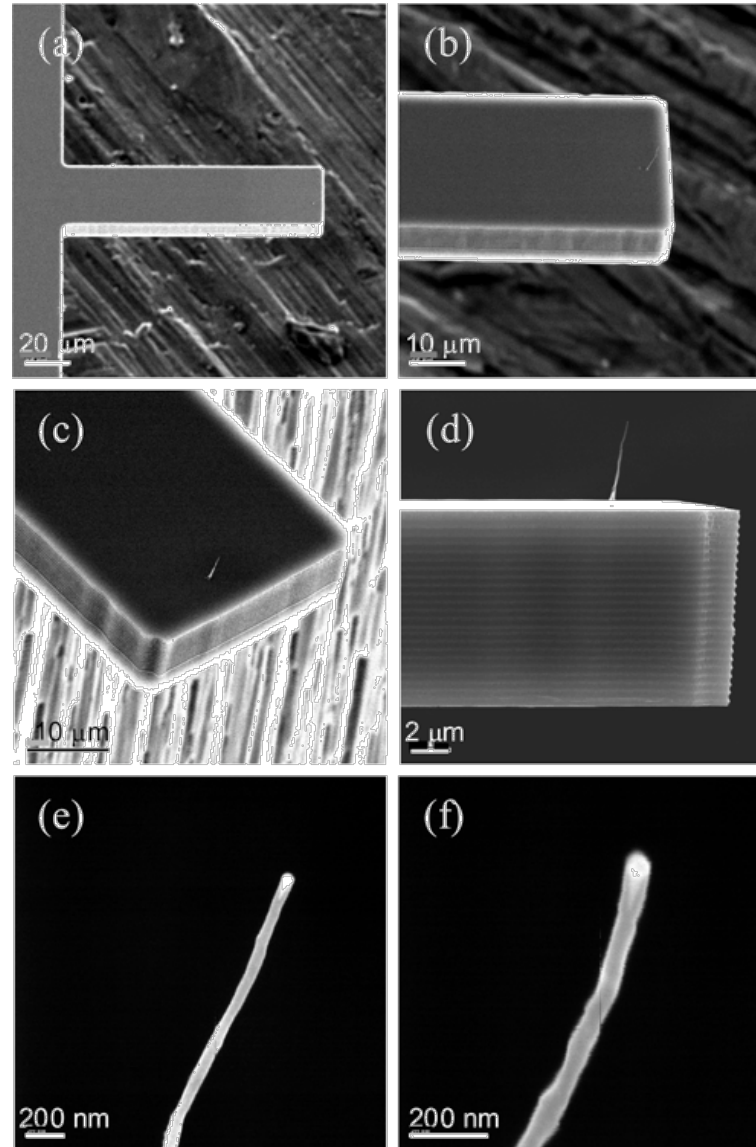
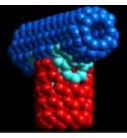


Each cantilever is  
1.6 mm x 3.44  
mm in size

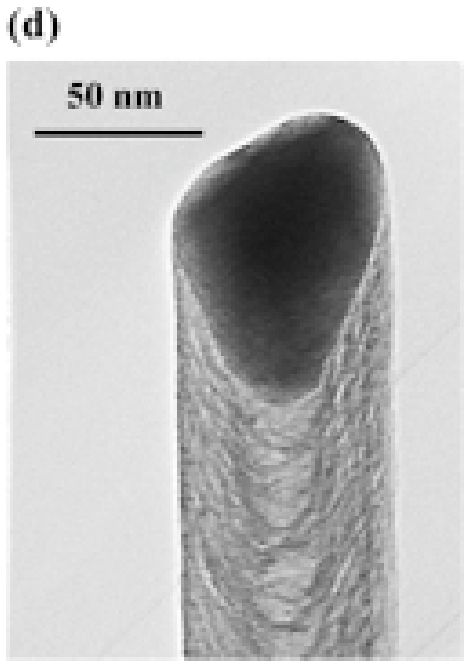
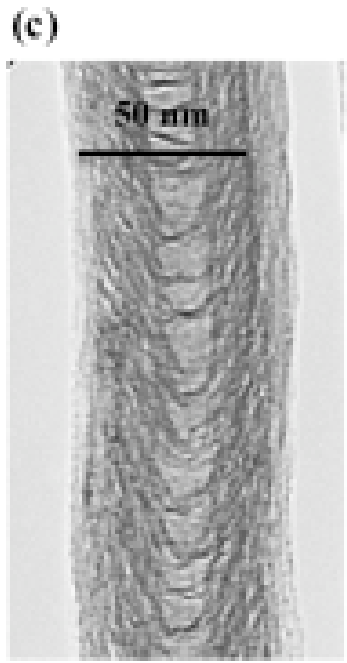
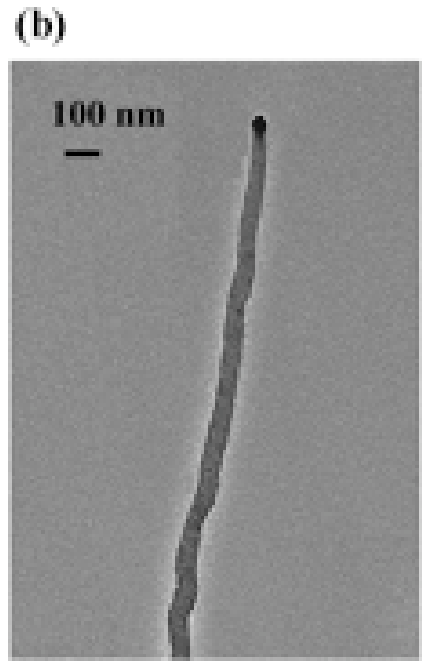
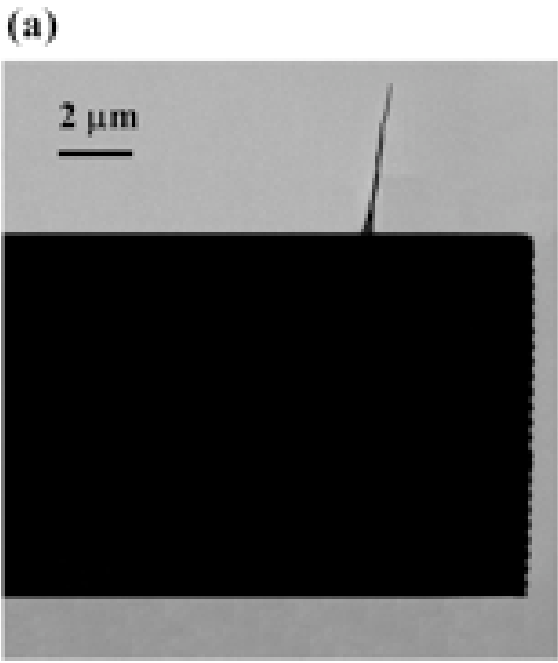
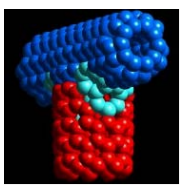


# Process Flow for CNT Probe Fabrication

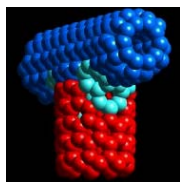




# Cross-sectional TEM Image

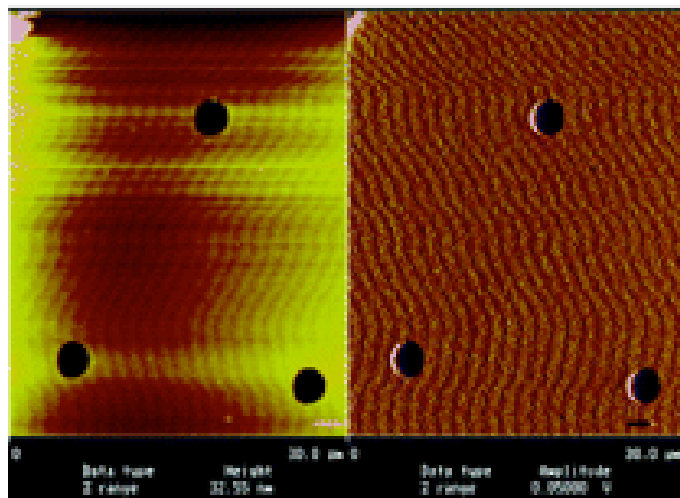


# Imaging using the CNT Probe

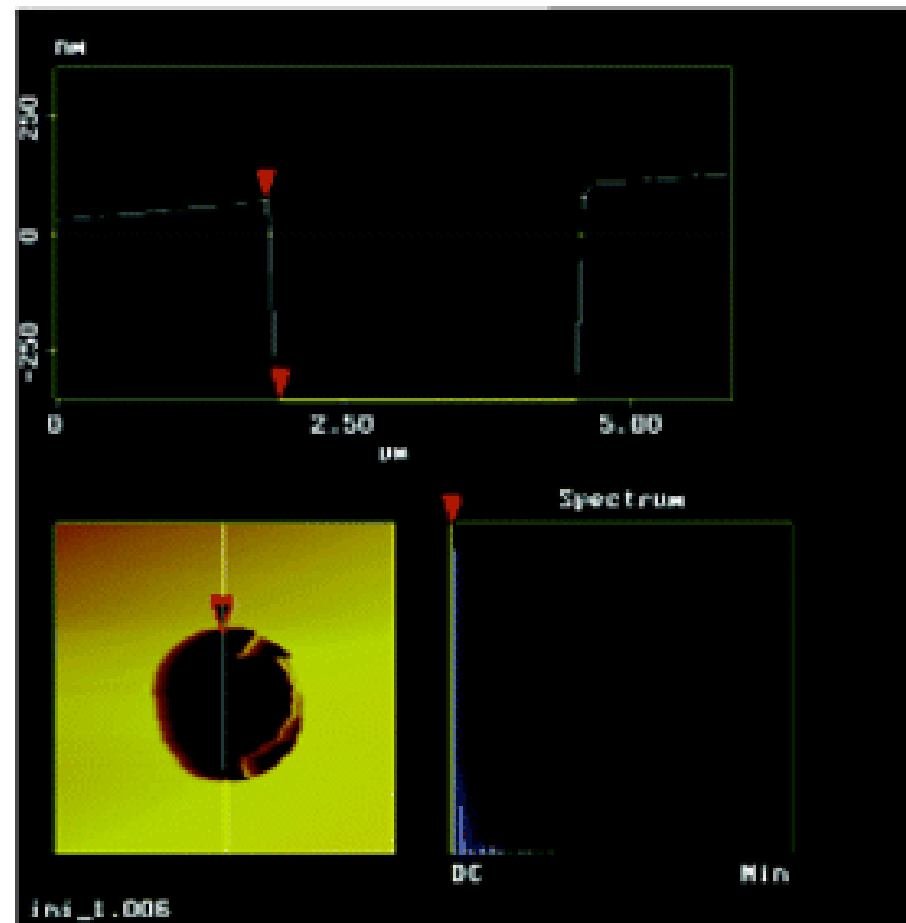


2  $\mu\text{m}$  dia hole, 400 nm deep in  $\text{Si}_3\text{N}_4$

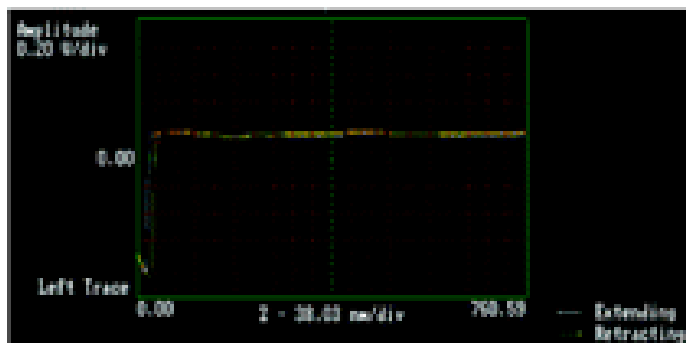
(a)

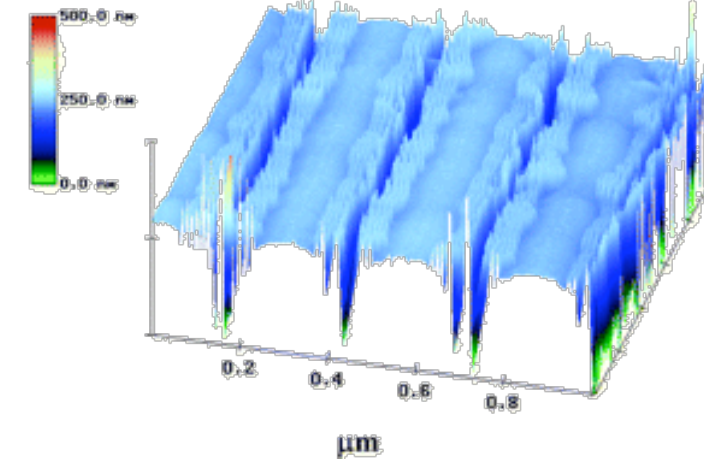
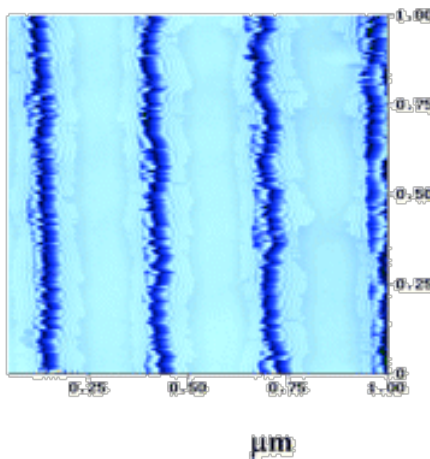
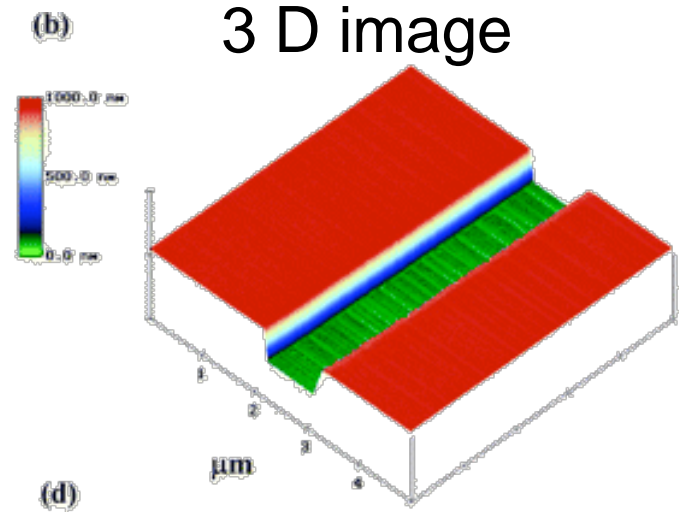
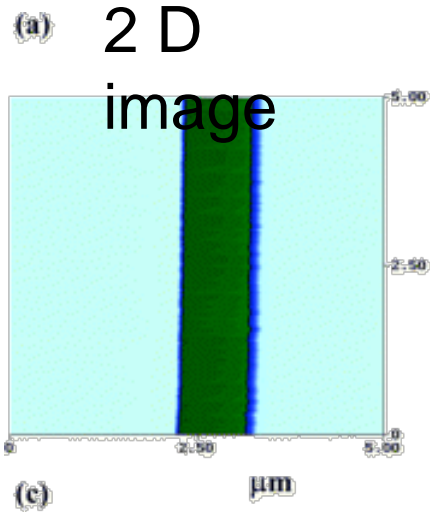
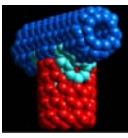


(c)



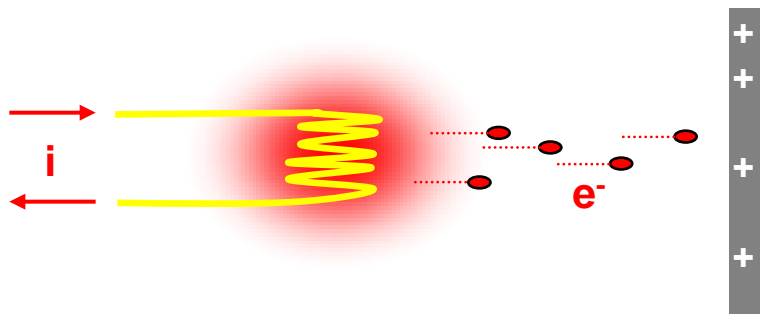
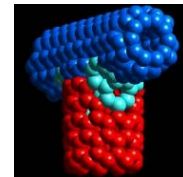
(b)



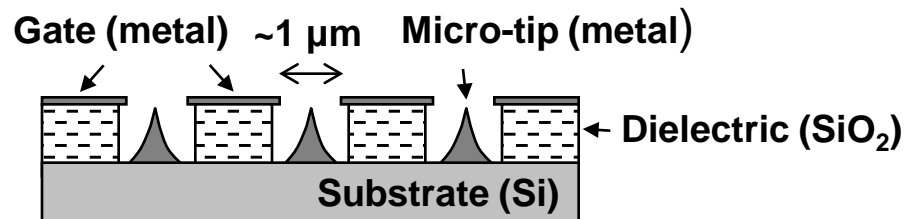


One micron trench (above) and 90 nm trench (below). Tip is 60 nm in diameter and 5  $\mu\text{m}$  long.

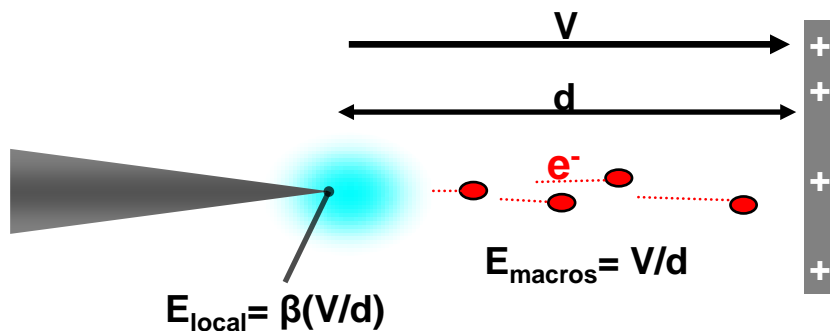
# Electron Emitters



Thermionic Emitter - W filament operating at 1000°C



Spindt Cathode - sharp Si tips  
Limited success: expensive to scale up

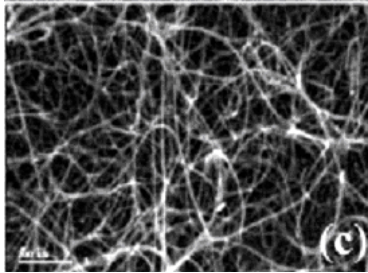
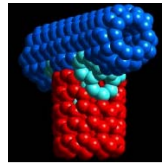


Cold Cathode Emitters

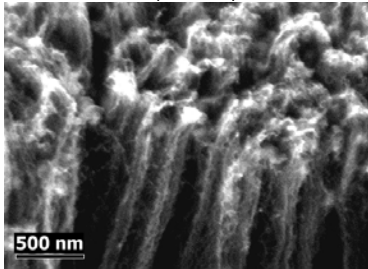
Threshold electric field at 10 mA/cm<sup>2</sup> (W. Zhu et al)

Material	Field (V/μm)
Mo and Si tips	50-100
P-type semi conducting diamond	130
Undoped defective CVD diamond	30-120
Amorphous diamond	20-40
CS-coated diamond	20-30
Graphite powder (<1mm)	17
Nanostructured diamond	3-5 (unstable >30mA/cm <sup>2</sup> )
Carbon nanotube (SWNT film)	1-3 (stable at 1A/cm <sup>2</sup> )

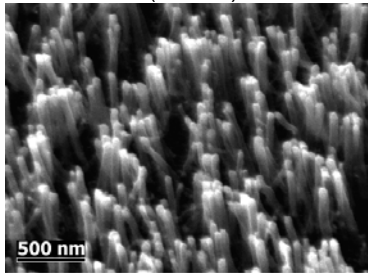
# Carbon Nanotubes in Field Emission Applications



Single wall nanotube (SWNT)

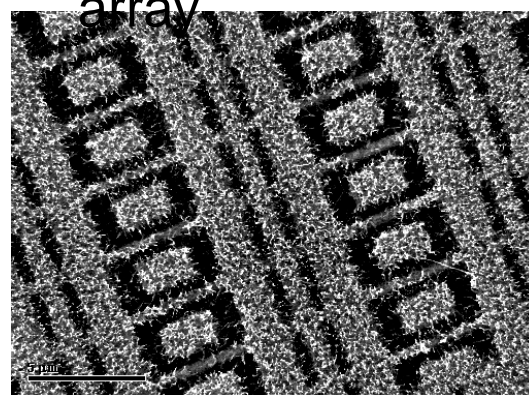


Multi wall nanotube (MWNT)



Nanofibers

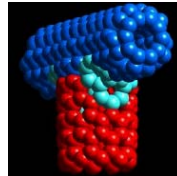
- Stable crystalline graphite structure
- Low turn-on fields
- Extremely sharp
- Very good conductor (up to  $10^9$  A/cm<sup>2</sup> local current density)
- Thermal tolerance (emission reported at 2000K)
- Mechanically robust
- Can be used as single emitter or large film / array



## Applications

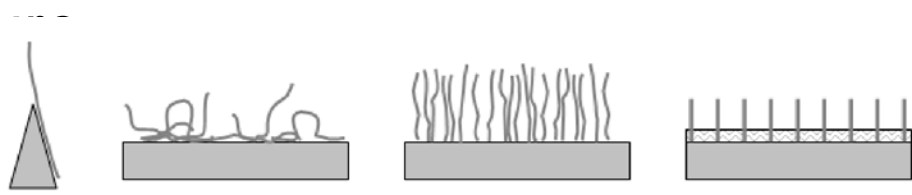
- Flat panel displays
- Lighting source
- X-ray tubes
- Instrumentation: SEM, mass spectrometer

# Structure of CNT Field Emitters

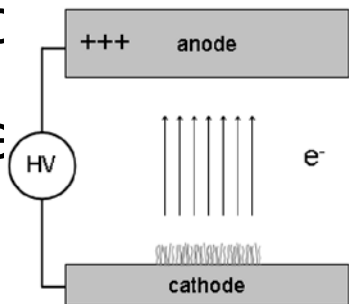


- Nature of nanotubes (SWCNTs, MWCNTs, CNFs...)
- Clean emitting sites vs. adsorbates (wafer vapor, oxygen...)

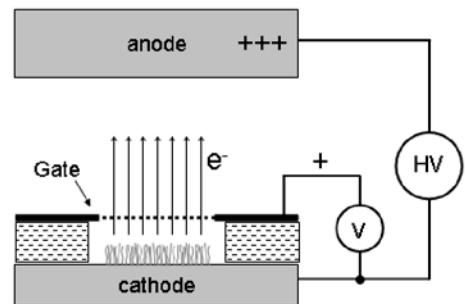
- Microstructures



- Screening effect
- Diode vs. triode



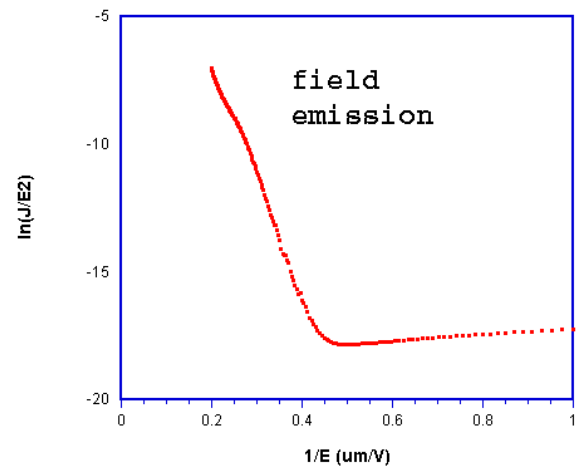
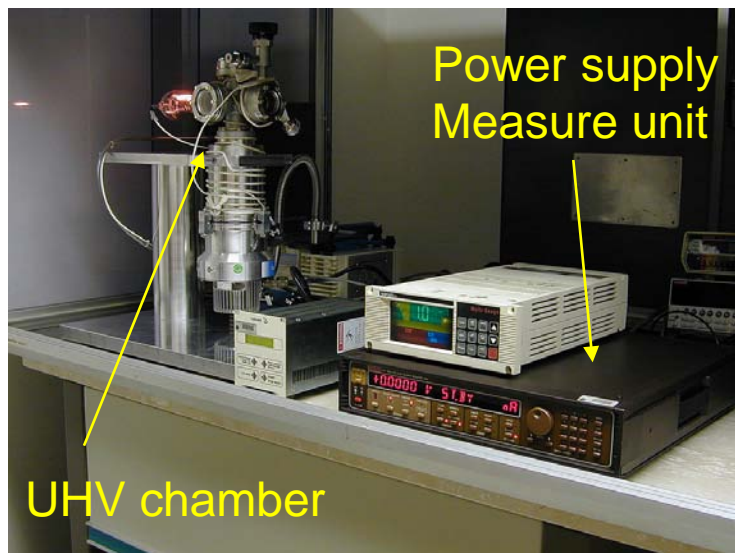
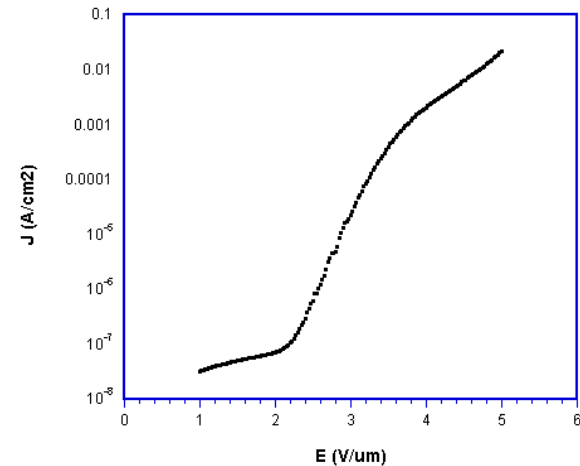
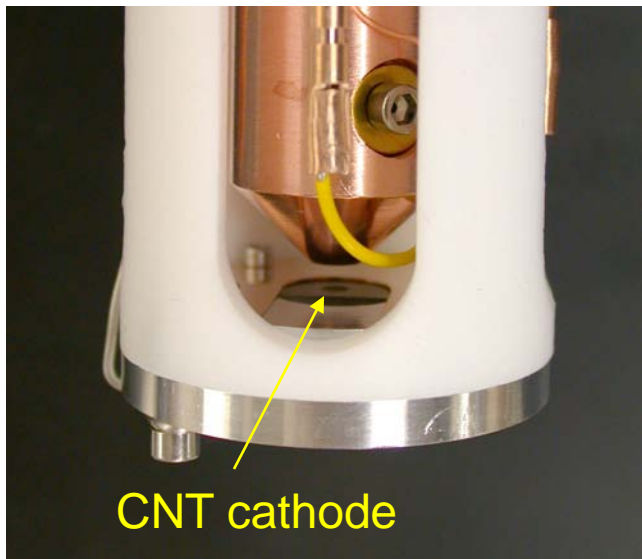
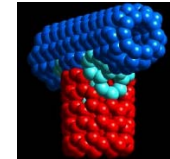
High voltage required and/or gap needs to be



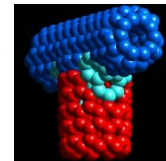
Current is controlled by gate voltage, independent of acceleration voltage



# Characterization of FE Properties

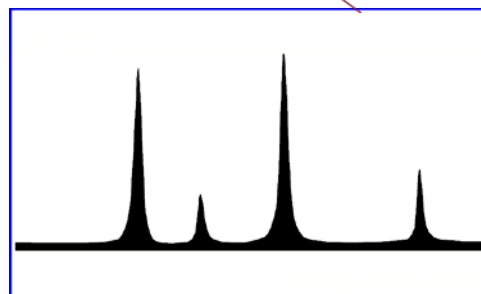
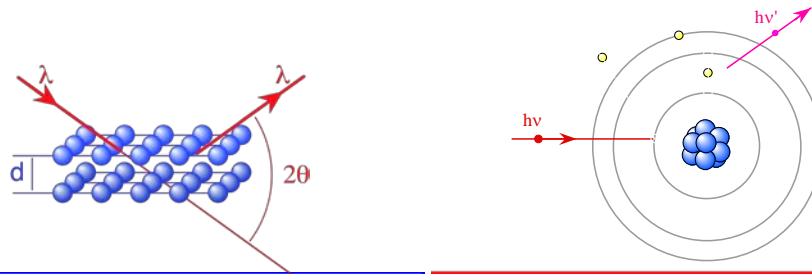


# CheMin X-Ray Diffraction/ X-Ray Fluorescence

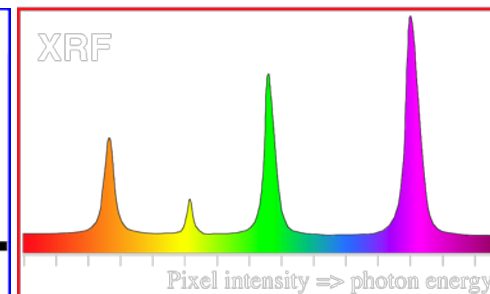


## Chemistry & Mineralogy

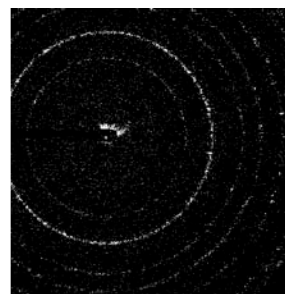
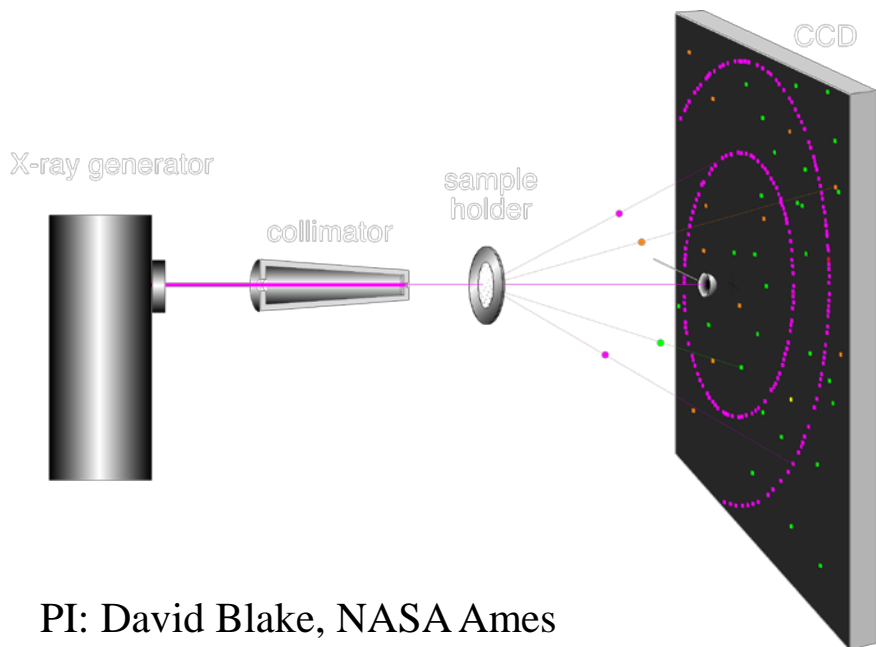
- 1 DETECTOR
- 2 SIMULTANEOUS ANALYSES
- NO MOVING PARTS



X-ray diffraction

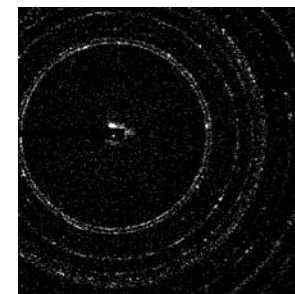


X-ray fluorescence



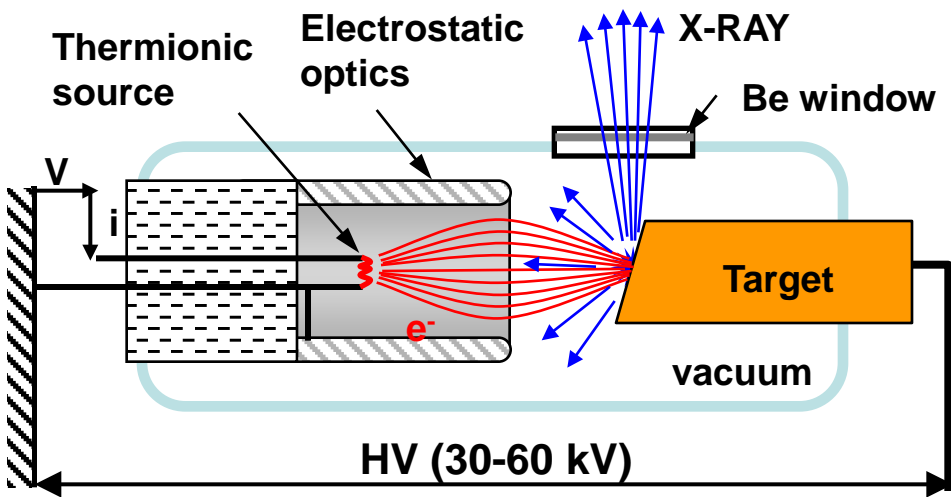
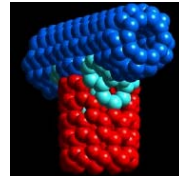
Calcite

$CaCO_3$



Aragonite

# X-ray Tube

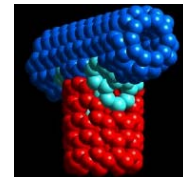


- ### CNT X-ray Tubes
- Beam spread of electrons and X-rays narrower
  - Lower power
  - Reduced heat load
  - Lower maintenance, longer life

### X-Ray Wavelength (nm)

<u>Target</u>	$K\beta_1$	$K\beta_2$	$K\alpha_1$	$K\alpha_2$
<b>Fe</b>	0.17566		0.17442	0.193604 0.193998
<b>Ni</b>	0.15001		0.14886	0.165791 0.166175
<b>Cu</b>	0.139222		0.138109	0.154056 0.154439
<b>Zr</b>	0.070173		0.068993	0.078593 0.079015
<b>Mo</b>	0.063229		0.062099	0.070930 0.071359

# Miniature CNT X-ray Tube in Flight Instrument



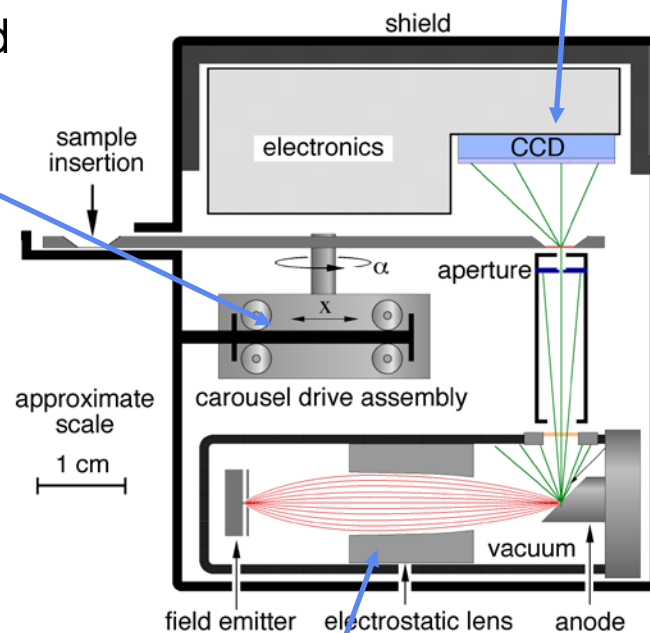
Integration in miniature X-ray tube  
(Oxford XTG Inc.)



## Flight instrument layout:

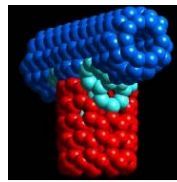
Various sample delivery configurations are studied

CCD detector optimized for X-ray detection

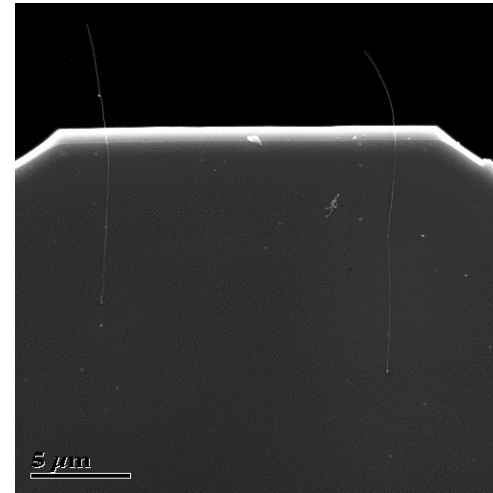
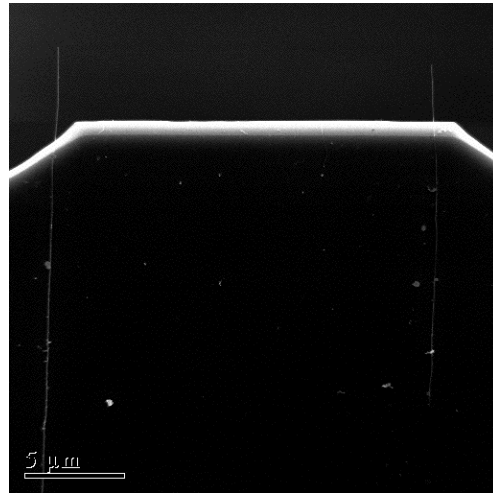


- volume < 1 liter
- mass < 1 kilogram
- power < 5 watts

miniature microfocused X-ray tube

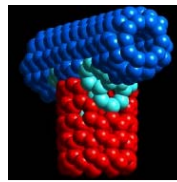


- Investigate field screening effect in a definitive manner
  - as a function of emitter separation
  - as a function of CNT length(Theory: field screening is minimized at separation  $> 2L$ )

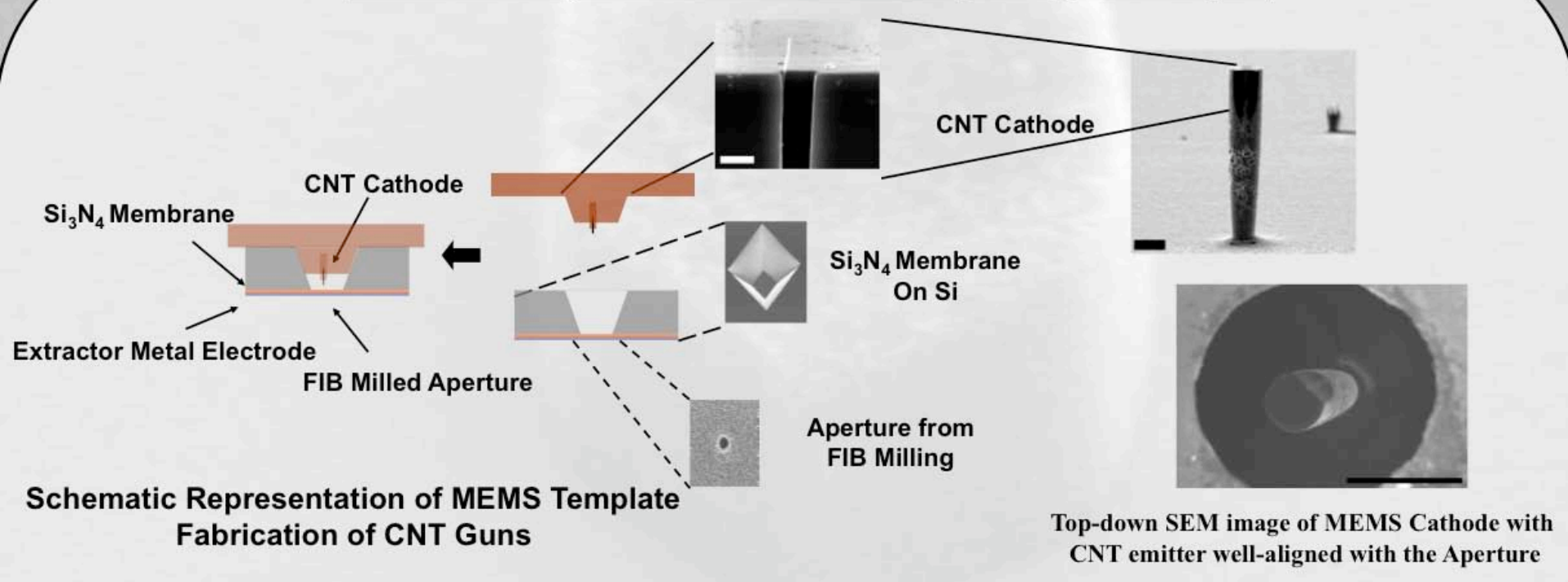


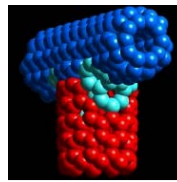
- Robustness and stability of the CNT emitter
- Electron optics optimization, anode target cooling (for baggage screening)
- Power supply design (takes up 90% of the volume), Packaging

# Single Electron Gun for a Microcolumn SEM

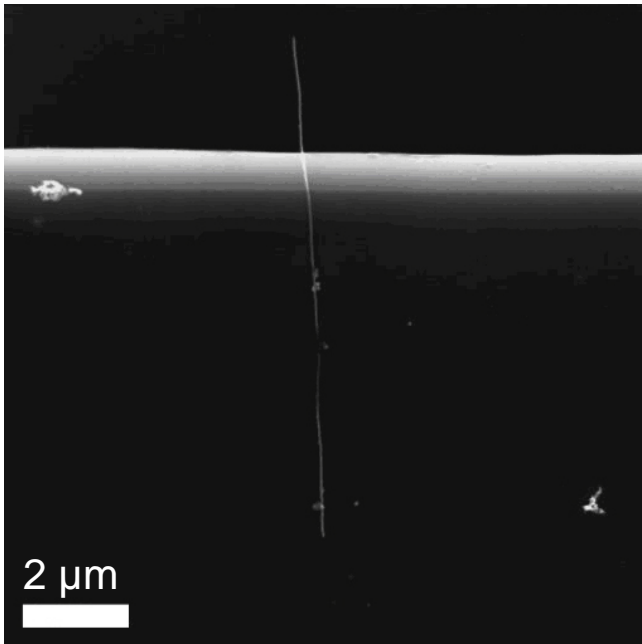


## Fabrication by MEMS Structural Templating Technique\*

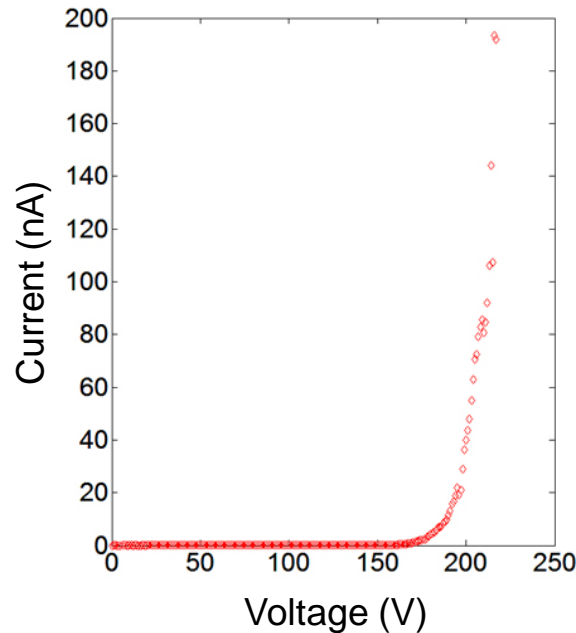




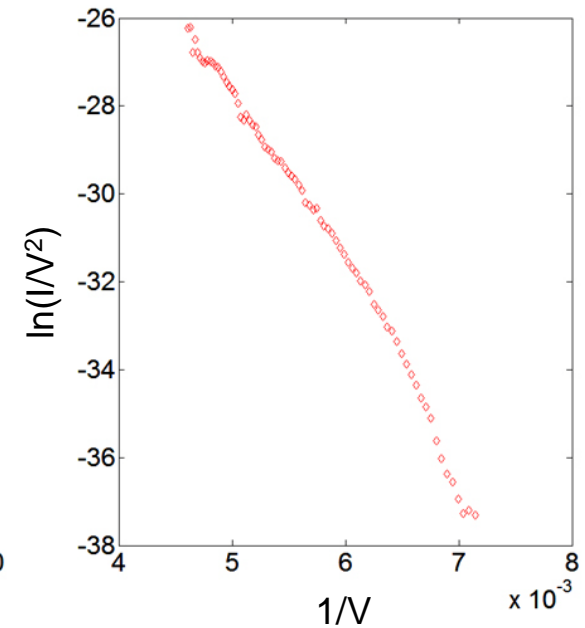
- MEMS based carbon nanotube cathode
  - Si structure coated with 25 nm Ni
  - Point electron source



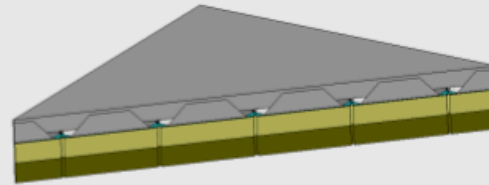
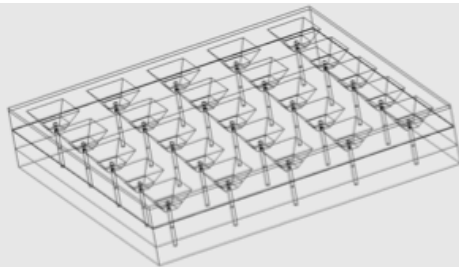
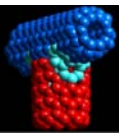
MEMS based nanotube cathode.



Field emission current-voltage data.

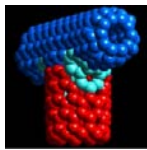


Fowler-Nordheim plot.

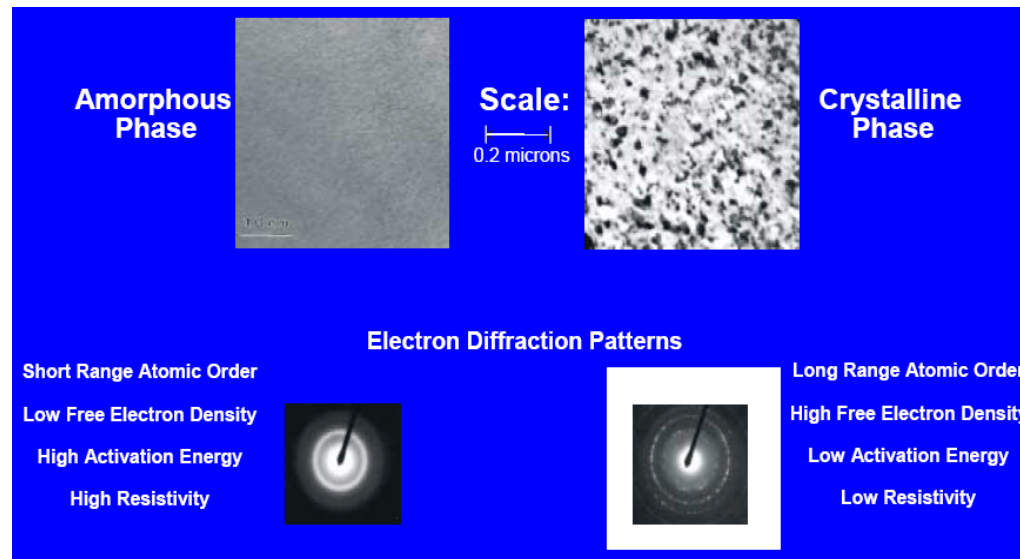


**5X5 Array of MEMS-based CNT electron guns fabricated by templating technique demonstrated above. Each gun in the array will be individually electrically addressable in order to precisely control dose exposure using voltage-controlled variable resistor circuit model that we developed above**

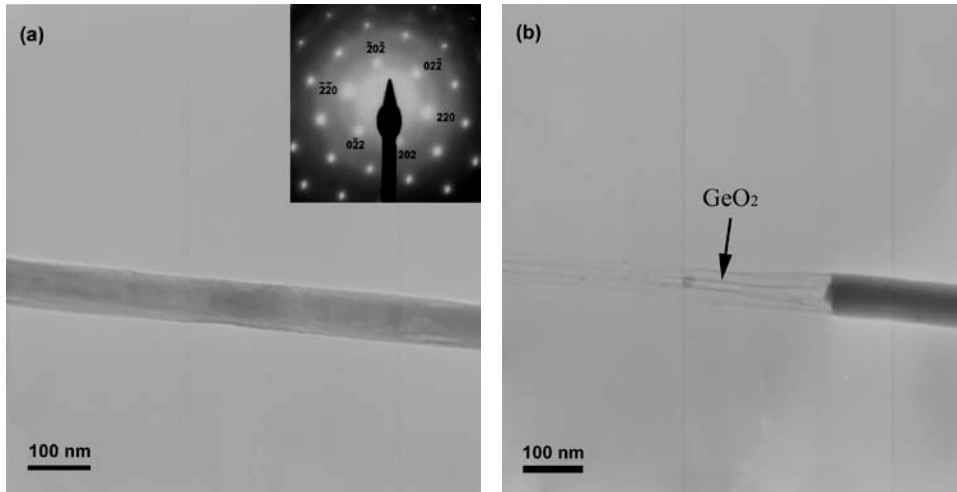
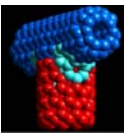




- Phase change materials date back to 1960s
  - Mainstream optical storage media (CD-RW, DVD-RW)
- Common phase-change material candidates
  - GeTe, **GeSbTe**,  $\text{In}_2\text{Se}_3$ , InSb, SbTe, GaSb, InSbTe, GaSeTe, ...

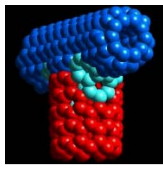


- Thermally induced phase change (orderly single crystalline or polycrystalline C-phase vs. less orderly amorphous  $\alpha$ -phase)



	GeTe (d=70nm)	In <sub>2</sub> Se <sub>3</sub> (d=40nm)
Bulk T <sub>m</sub>	725°C	890°C
Nanowire T <sub>m</sub>	390°C	680°C
Reduction	46%	24%

- The melting temperature of the phase-change nanowire is identified as the point at which (1) the electron diffraction pattern disappears and (2) the nanowire starts to evaporate.
- This property is diameter-dependent: reduction even more significant for smaller diameters



- Nanomaterials, because of a change in properties relative to their bulk counterparts, can have an impact on construction of probes, diagnostic equipment and sensors.
- For example, we have used carbon nanotubes successfully in AFM-based metrology, and miniaturization of analytical equipment.